PRIOR INFORMATION NOTICE

Supplies

Directive 2014/24/EU

This notice is for prior information only

SECTION I: CONTRACTING AUTHORITY

I.1) NAME AND ADDRESSES

Official name:
Technische Universiteit Delft
National ID:
27364265 0001
Postal address:
Stevinweg 1
Town:
Delft
NUTS code:
NL
Postal code:
2628 CN
Country:
NL
Contact person:
Jordy Rog
Telephone:
+31 0628743101
E-mail:
procurement@tudelft.nl
Fax:
-

Internet address(es)

Main address:
http://www.tudelft.nl
Address of the buyer profile:
https://platform.negometrix.com/PublishedTenders.aspx?tenderid=174533

I.2) JOINT PROCUREMENT

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I.3) COMMUNICATION

Additional information can be obtained from

the abovementioned address

I.4) TYPE OF THE CONTRACTING AUTHORITY

Body governed by public law

I.5) MAIN ACTIVITY

- Education

SECTION II: OBJECT

II.1) SCOPE OF THE PROCUREMENT

II.1.1) Title

ICP Oxide etcher

Reference number: -

II.1.2) CPV code(s)

Main code:

38000000 - Laboratoriuminstrumenten, optische en precisie-instrumenten (uitgezonderd brillen)

Supplementary code:

-

II.1.3) Type of contract

Supplies

II.1.4) Short description

At this moment KN wants to replace a 20+ year old oxide etcher. The KN is seeking an ICP-RIE system, with RF bias, capable of running recipes with high SiO2 etch rate (about 1 um/min) to a 50um depth and with 5-10um wide trenches on 4 inch wafers and smaller samples.

II.1.5) Estimated total value

Value excluding VAT: - Currency: -

II.1.6) Information about lots

This contract is divided into lots: no

II.2) DESCRIPTION

II.2.1) Title

-

Lot No: -

II.2.2) Additional CPV code(s)

-

II.2.3) Place of performance

NUTS code:
NL NEDERLAND

Main site or place of performance:
-

II.2.4) Description of the procurement:

(nature and quantity of works, supplies or services or indication of needs and requirements)

Kavli Nanolab (KN) is a nanofabrication cleanroom facility for the scientific community of TU Delft (TUD) and external public parties, and also for external companies. The equipment in this facility is owned and maintained by the staff members and operated by users. This could for instance mean that on each individual tool can have more than 100 authorized users. The facility and its tools are heavily used, typically more than 1500 hours per year.

At this moment KN wants to replace a 20+ year old oxide etcher. The KN is seeking an ICP-RIE system, with RF bias, capable of running recipes with high SiO2 etch rate (about 1 um/min) to a 50um depth and with 5-10um wide trenches on 4 inch wafers and smaller samples.

We expect more than one supplier can meet our requirements and therefore we need to do a market consultation in order to get a detailed overview of suppliers and their capabilities. In particular TUD will focus on ease of operation in a multi-user operation and on proven process output.

II.2.14) Additional information:

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II.3) ESTIMATED DATE OF PUBLICATION OF CONTRACT NOTICE

01/06/2021

SECTION IV: PROCEDURE

IV.1) DESCRIPTION

IV.1.8) Information about the Government Procurement Agreement (GPA)

The procurement is covered by the Government Procurement Agreement: yes

SECTION VI: COMPLEMENTARY INFORMATION

VI.3) ADDITIONAL INFORMATION

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VI.5) DATE OF DISPATCH OF THIS NOTICE

31/03/2021